Application of the ATOMKI-ECRIS for materials research and prospects of the medical utilization

Sándor Biri

Institute of Nuclear Research (ATOMKI) ECR Laboratory Debrecen, Hungary

Co-authors:

•ATOMKI: I. Iván, Z. Juhász, B. Sulik,
 •Univ. Deb.: Cs. Hegedűs, A. Jenei, S. Kökényesi, J. Pálinkás

Collaborators:

•National Institute of Radiological Sciences (NIRS), Chiba, Japan

•Bio-Nano Electronics Research centre, Toyo University, Kawagoe, Japan

• Division of Electrical Engineering, Osaka University, Osaka, Japan

• Tateyama Machine Co., Ltd., Toyama, Japan

Outline

Introduction

- 1. New fullerene-based materials to be produced in ECR discharge
- 2. Bone cell growth on titanium coated with fullerene.
- 3. Optical changes in thin films by HCI irradiation
- Guiding of HCI through nano- and micro-capillaries
 Comparison, summary



• 14.3 GHz/1 kW

- Axial field:1.2/0.4/1.0 T
- Radial field: 0.9 T
- Chamber: φ58x200
- Extraction: 0.2-30 KV

Two versions of the ECRIS



Fullerene-based new materials (C₆₀+X) to be produced in ECR-discharge

Since 2000 fullerene plasmas and beams have been produced at the ATOMKI ECRIS

- C₆₀: just a working material (as Ne, Ar, Fe), no "C₆₀ research"
- Production of C₆₀ ion beam (intensity, charge)
- Fullerene derivatives (destroyingadding)
- Mixture plasmas (C₆₀+X)
- New materials (by C₆₀+X) to detect in beam
- New materials to produce in macroscopic quantity
- Applications (surface coating, etc.)





Basic C60 experiments









Iron encapsulated in fullerene

| Ha X=Fe \rightarrow Fe@C ₆₀ |
|--|
| Nanotechnology |
| new SC materials |
| quantum computing |
| Medical tratments |
| ultra-contrast Magnetic Resonance Imaging (M |
| magnetic nano-particle |

In ECR ion sources:

- Evaporation of C₆₀ is solved (500 C)
- Production of fullerene derivatives is possible
- such as (C60)+, (C58)+, (C56)+,..., (C60)++, (C58)++, (C56)++,...,
- Calculations showed that fullerene derivatives are less stable
- Therefore we must make a two-components plasma
- 1. component: C_{60} (mass and charge to be regulated)
- 2. component: Fe: pure iron "gas", positive ions with optimal energy
- Synthesis: volume or surface?





Iron plasma in ECR ion sources (pre-experiments)

 Filament ovens: high temperature, large size, impurities

Sputtering: high microwave power, high voltage,

•Sublimation: omly in chemical compounds, e.g. ferrocene $Fe(C_5H_5)_2$: many non-wanted C, H, C_xH_x

•External ion source (e.g. MEVVA): complicated
 to connect (?)

Indution oven: only iron!









It was decided to build a new ECR ion source at Toyo University, Kawagoe, Japan. To produce new, fullerene-based materials, mainly metal-encapsulated fullerenes. It is called: Bio-Nano-ECRIS Collaborators: Toyo Univ., NIRS, Osaka Univ., Tateyama Co. and ATOMKI 1st step: geometry and magnetic trap



The Bio-Nano-ECRIS project at Toyo University

- Geometry: plasma chamber OD=14 cm, L=35 cm.
- Microwave: 8-10 GHz, optional 2.45 GHz 2nd frequency.
- Mirror field: 2 identical RT-coils, max. 0.64 Tesla.
- Hexapole: NdFeB, modified AECR-U design, 0.72/0.45 Tesla.
- Fullerene gas: using simple filament oven or evaporation boat.
- Iron gas: by induction oven (under development).
- Beamline: AM to transport upto 5 KV beams with M=800.
- First gas plasma: 2008 March
- Fe+C60 mixing: 2009-2010



Induction oven, under development



Bio-Nano-ECRIS, Toyo University, 2008

2. Bone cell growth on titanium coated with fullerene.

ATOMKI ECRIS Group and Unideb Faculty of Dentistry collaboration



- Task: irradiate simultaneously 10 Ti samples
- Size: 10x10x0.5 mm (d=50 mm beam is necessary)
- ATOMKI-ECRIS-B configuration
- Primary beamline, 50 cm distance from plasma
- 90% of the beam is single-charged
- 80% of the extracted beam is fullerene
- 90 deg beamline: just composition check
- U=250 V and U=500 V extraction voltages
- beam accuracy on 5 segments: less than 10% difference
- total intensity hit the samples: 300-800 enA
- C60 thickness estimated: 1 and 5 layers



Summary of the Ti coatings by C60

| Ti sample series | C ₆₀ fraction in beam (%) | Beam energy (eV) | Number of C ₆₀ molecular layers on the Ti surface | Time of irradiation (min) |
|------------------------|--|------------------------|--|---------------------------------|
| 1 | 80 | 500 | 4.3 | 90 |
| 2 | 93 | 500 | 1.2 | 23 |
| 3 | 74 | 250 | 4.9 | 87 |
| 4 | 84 | 250 | 1.1 | 32 |

Human embryonic bone cells were cultured onto the Ti substrates for 48 hours (type: palatal mesenchymal pre-osteoblast, HEPM 1486, ATCC)
Cells dual labeled with special markers (FITC-falloidin), actine and vinculine
Confocal imaging: laser scanning microscope (LSM 510, Carl Zeiss).



Bone cells grown on glass

Bone cells grown on Ti+C60 (250 eV)

The morphology of the cells is different compared to the control substrate The control cells on glass are quite spread showing an interconnected morphology The cells grown on the Ti substrates are more spindle-like shape showing denser actine and vinculine structure

But there is no remarkable difference between the four Ti+C60 series, so far.

Glass:



This first experiment: successful Proved: C60 coating does not prevent bone cells grows. High number of bone cells grew on Ti+C60 (~5*10⁵/cm3) Further experiments: optimal beam properties (energy, rate, density, composition) Goal: improve physical (Ti-C60) and biological (C60-cells) properties

3. Modificaction of thin films by multiply charged ions

2004-2006: individual slow ions hitting the surface
Amorphous Se layers, 500 nm, on mica
Needle-like SbSJ crystals





- Xe gas natural
- •Charge: 20+, 24+
- •Ion flux: 1-100 ion/nm²
- •Extraction voltage: U= 4...10 KV

Surface structuring - AFM photos



Xe^{20...24+} E= 120-240 keV

Production of surface micro and nanostructures in one step without etching

Hillocks!

One possible mechanism of nano-hillock formation consists in the process, similar to the radiation-stimulated creation and diffusion of defects to the drains at the surface.

2007-2008: volume effects

Precedents

- Laser induced structural changes
- •Ion irradiation induced structural changes (H^+ , D^+)

 $\cdot As_2S_3$, AsSe, Se

- Ions: Neq+ (q=4...8)
- Ekin = 120 keV fixed
- Sample: AsSe layer on glass
- d=700 nm
- Penetration depth R= 200 nm
- Measured parameter: darkening (T/T₀) depending on the charge





 $T/T_0 = \exp(-ad) \approx \exp(-a_1R) \exp(-a(d-R)) \approx \exp(-a_1R) const$







Our experiment showed that $(T/TO)_{sat}$ is larger for the sample irradiated with Ne8+ ions than for the one irradiated with Ne4+ ions.

Global optical property can be effected by the charge!

4. Guiding of slow, highly charged ions through nano-capillaries

Ions with few keV energy have been transmitted through capillaries of thin PET and S_iO₂ insulating foils
 There was significant transmission even if the capillaries were tilted by large angles, i.e., when there is no geometrical transparency for straight line trajectories.
 The initial charge state may be or may be not changed.



2004-2008: ATOMKI-ECRIS-A

- Target: membranes of nanochanneled Al₂O₃, thickness 15 µm, honeycomb
- capillary diameters: 140-260 nm
- to prevent charging up: 20 nm Nb layers
- Neon (6+, 7+), argon (8+, 9+)
- Extraction: 500 V
- Beam: two 1 mm diaphragms at 205 mm
- Beam current 300-500 pA
- Detectors: FC, ion-spectrometer (channeltron), multi-channel-plate (MCP)









Experimental setup







Comparison and summary

| Project short name: | Endohedral fullerenes | Ti implants coating | Thin layer modification | Capillary guiding |
|------------------------------|--|---|------------------------------|---|
| Ion source: | ATOMKI-ECRIS-B and Bio-Nano-ECRIS | ATOMKI-ECRIS-B | ATOMKI-ECRIS-A | ATOMKI-ECRIS-A |
| Plasma/beam: | Fe ⁺ , C ₆₀ ⁺ | C_{60}^{+} | Ne ⁴⁺⁸⁺ | Ne ^{6+,7+} , Ar ^{8+,9+} |
| Beam diameter (mm) | 10-20 | 50 | 4 | 1 |
| Extraction voltage (V) | 500-5000 | 250-500 | 15000-30000 | 500-1000 |
| Microwave frequency (GHz) | 8-12 | 12-14 | 14.3 | 14.3 |
| Microwave power (W) | 1-50 | 4-20 | 200-400 | 200-600 |
| Specification: | Synthesis in plasma or on surface | Irradiation in the zero-degree beamline | Beams with same total energy | Puller on high negative voltage |

The tasks and beam requirements were different, but the ECR source proved to be versatile enough to fulfill all these jobs and serves as a very useful multi-purpose facility.

Thank you for your attention!